

(12) United States Patent

Hush et al.

US 7,869,249 B2 (10) Patent No.: (45) **Date of Patent:** Jan. 11, 2011

(54) COMPLEMENTARY BIT PCRAM SENSE AMPLIFIER AND METHOD OF OPERATION

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Notice: Subject to any disclaimer, the term of this

patent is extended or adjusted under 35

U.S.C. 154(b) by 453 days.

Appl. No.: 12/073,901

(22)Filed: Mar. 11, 2008

(65)**Prior Publication Data**

> US 2008/0225571 A1 Sep. 18, 2008

Related U.S. Application Data

- Continuation of application No. 11/476,043, filed on Jun. 28, 2006, now Pat. No. 7,366,003, which is a division of application No. 11/236,562, filed on Sep. 28, 2005, now Pat. No. 7,242,603, which is a division of application No. 10/866,091, filed on Jun. 14, 2004, now Pat. No. 7,002,833, which is a continuation of application No. 09/988,627, filed on Nov. 20, 2001, now Pat. No. 6,791,859.
- (51) Int. Cl. G11C 17/00 (2006.01)
- Field of Classification Search 365/100, 365/148, 222 See application file for complete search history.

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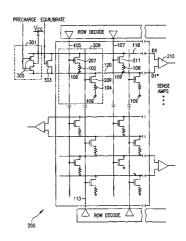
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ABSTRACT

A method and apparatus is disclosed for sensing the resistance state of a Programmable Conductor Random Access Memory (PCRAM) element using complementary PCRAM elements, one holding the resistance state being sensed and the other holding a complementary resistance state. A sense amplifier detects voltages discharging through the high and low resistance elements to determine the resistance state of an element being read.

20 Claims, 6 Drawing Sheets



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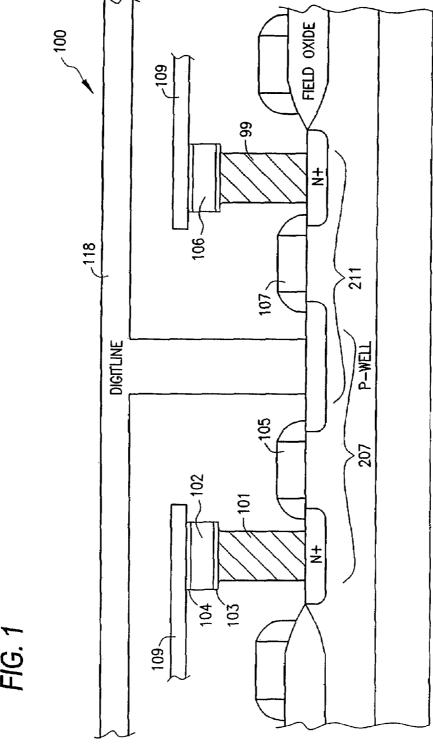
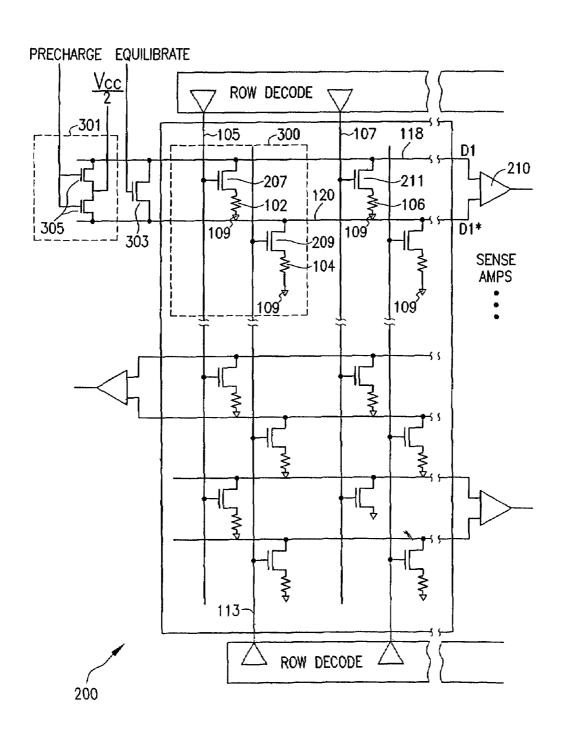
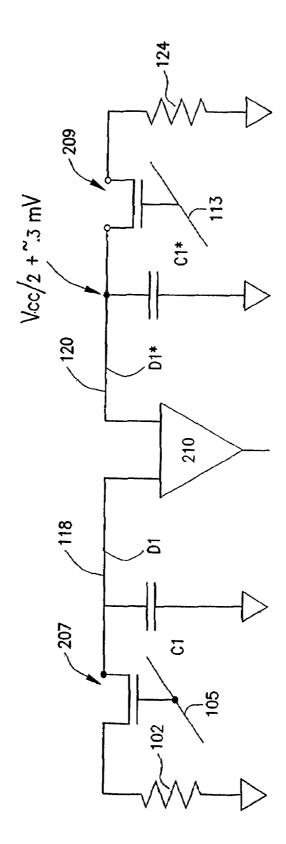


FIG. 2





F1G. 3

D1* 5 306 308 304 PSENSE-AMP 310 -

FIG. 5

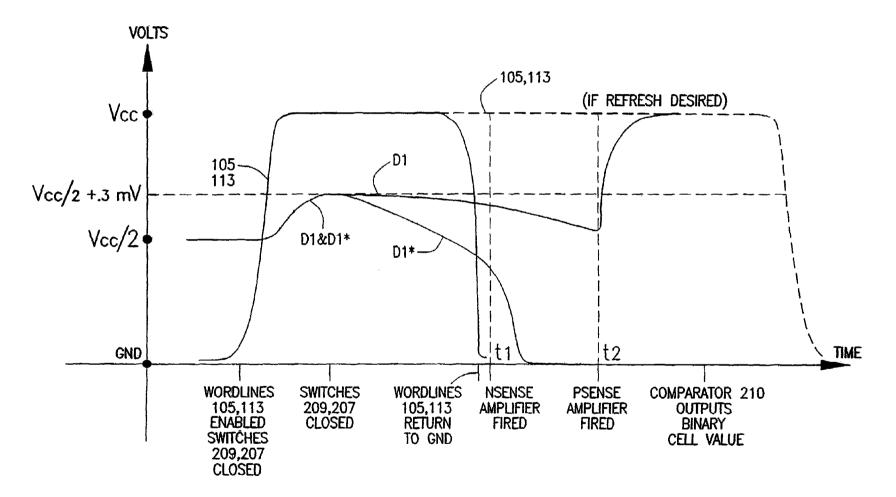
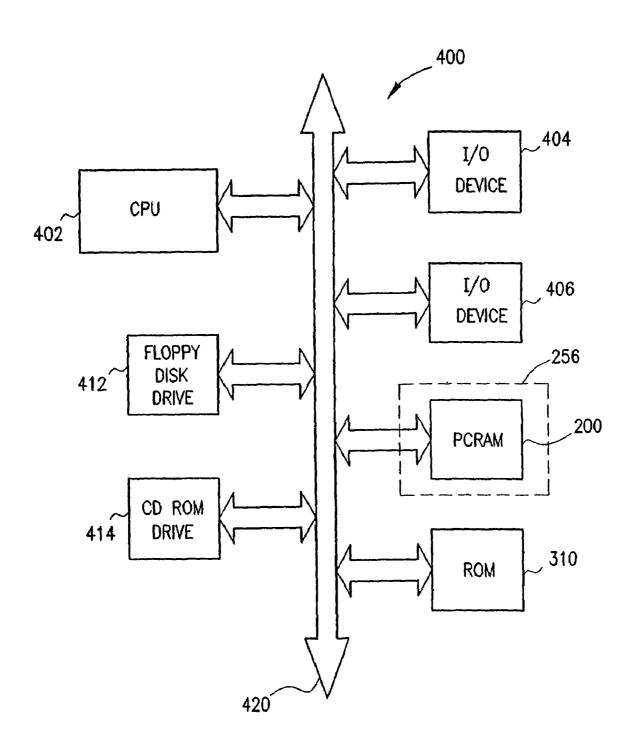


FIG. 6



COMPLEMENTARY BIT PCRAM SENSE AMPLIFIER AND METHOD OF OPERATION

CROSS REFERENCE TO RELATED APPLICATIONS

The present application is a continuation of U.S. application Ser. No. 11/476,043, filed on Jun. 28, 2006 now U.S. Pat. No. 7,366,003, which in turn is a divisional of Application No. 11/236,562, filed Sep. 28, 2005, now U.S. Pat. No. 7,242, 10 603, which is a divisional of application No. 10/866,091, filed Jun. 14, 2004, now U.S. Pat. No. 7,002,833, which is a continuation of Application No. 09/988,627, filed Nov. 20, 2001, now U.S. Pat. No. 6,791,859, the disclosures of which are herewith incorporated by reference in their entirety.

FIELD OF THE INVENTION

The invention relates to a method and apparatus for sensing the resistance of a Programmable Conductor Random Access Memory (PCRAM) element.

BACKGROUND OF THE INVENTION

PCRAM devices store binary data as two different resistance values, one higher than the other. The resistance value represents a particular binary value of logic "0" or logic "1". When sensing the resistance value of a PCRAM device, it is common to compare the resistance of a memory cell undergoing a read operation with resistance of a reference cell to determine the resistance value of the cell being read and thus its logic state. Such an approach is disclosed in U.S. Pat. No. 5,883,827. However, this approach has some limitations.

If the reference cell is defective and a column of memory cells within an array uses a same defective reference cell, the entire column of memory cells will have erroneous resistance readings. In addition, specialized circuitry is required to write a resistance value into the reference cell, and a sense amplifier circuit for such an arrangement tends to be complex and large.

Typically, sensing schemes for PCRAM devices also tend to have a unique architecture which is different from that normally employed in typical DRAM circuits. Although PCRAM's differ from DRAM's in that they store binary values in resistive memory elements rather than as charges on capacitors, and although PCRAM's are non-volatile, where the capacitor structures employed in DRAM's are volatile, nevertheless it would be desirable if the read and write circuits for both devices were as similar as possible so that existing DRAM memory device architectures could be easily adapted to read and write PCRAM devices.

BRIEF SUMMARY OF THE INVENTION

The present invention provides a PCRAM memory device 55 and its method of operation which utilizes a read architecture similar to that employed in some DRAM memory devices. A pair of complementary PCRAM memory cells comprising first and second programmable conductor memory elements are employed, each connected to respective access transistors. During a write operation, the first and second memory elements are written with complementary binary values, that is: if the first memory element is written to a high resistance state, then the second memory element is written to a low resistance state; whereas if the first memory element is written to a low resistance state, the second memory element is written to a higher resistance state.

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During a read operation of, for example, the first memory element, a sense amplifier is connected so that its respective inputs are coupled to receive respective precharge voltages which discharge through the first and second memory elements. A sense amplifier reads the discharging voltages through the two memory elements to determine which is the larger voltage, thus determining the resistance (high or low) and logic state (high or low) of the memory cell being read.

BRIEF DESCRIPTION OF THE DRAWINGS

These and other features and advantages of the invention will become more apparent from the following detailed description of exemplary embodiments of the invention which are provided in connection with the accompanying drawings in which:

FIG. 1 shows an exemplary PCRAM device;

FIG. 2 is a schematic diagram depicting one aspect of the invention;

FIG. 3 is a schematic diagram depicting an additional aspect of the invention;

FIG. 4 is a schematic diagram depicting an additional aspect of the invention;

FIG. 5 shows the discharge rate characteristics of capacitors employed in the invention;

FIG. 6 shows the invention utilized in a computer system.

DETAILED DESCRIPTION OF THE INVENTION

The present invention employs a sense amplifier architecture which is somewhat similar to that employed in some conventional DRAM devices to sense the resistance states of PCRAM memory cells. In the invention, a binary value is stored as a resistance value in a first PCRAM cell while its complement resistance value is stored in a second PCRAM cell. During readout of the first PCRAM cell, both PCRAM cells are used to discharge a precharge voltage into respective inputs of a sense amplifier which reads the discharge voltages to determine the resistance and thus the binary value stored in the first PCRAM cell undergoing a read operation.

FIG. 1 illustrates an exemplary cell arrangement provided within a portion of a PCRAM memory device constructed in accordance with the invention. A PCRAM memory element 102 is illustrated which has a chalcogenite glass body and lower 103 and upper 104 conductors. As is well known, a programmable conductor memory element has two stable resistance states: one high resistance and one low resistance. Normally, when at rest the memory has a high resistance state, but it can be programmed to a low resistance state by suitably applying bias voltages to the conductors 103 and 104. Typically, the low resistant state of a PCRAM memory element is characterized by a dendrite growth through the chalcogenite glass body or along the surface of the chalcogenite glass body between the conductors 103 and 104. A high resistant state is present when there is no such dendrite growth. The grown dendrite is relatively non-volatile in that it will remain in place for a relatively long time, e.g. days or weeks, after the bias voltage is removed.

As further shown in FIG. 1, the PCRAM memory element 102 is coupled by a conductive plug 101 to an access transistor 207 which is driven by a word line 105 which forms the gate structure of transistor 207. The access transistor is coupled through conductive plug 101 to one of the conductors 103 of the PCRAM memory element. The other conductor 104 of the PCRAM element is connected by a common cell plate 109 to a bias voltage, which is common to other PCRAM memory elements provided in the memory device.

FIG. 1 illustrates a common PCRAM architecture in which two adjacent memory cells 207, 211 are coupled to a common digit line 118. Thus, FIG. 1 also shows another access transistor 211 driven by a word line 107 which is connected through conductive plug 99 to another PCRAM memory element 104, which in turn is also connected also to the common cell plate 109. Access transistor 211 also has one terminal connected to digit line 118.

FIG. 2 shows an electrical schematic arrangement of a memory array employing the cell architecture illustrated in 10 FIG. 1. Thus, the top portion of FIG. 2 illustrates the transistors 207 and 211 coupled to the respective PCRAM memory elements 102 and 106 with the access transistors 207 and 211 coupling the memory elements 102 and 106 to the digit line 118.

As also illustrated in FIG. 2, a complementary digit line D1* 120 is also provided in the memory array, to which another set of access transistors is connected which are in turn connected to other PCRAM memory elements. To simplify discussion, a single complementary pair of PCRAM cells is 20 illustrated as 300. It includes transistor 207 and associated PCRAM memory element 102, which is coupled to the digit line 118 (D1), and an access transistor 209 and associated PCRAM memory element 124, which are coupled to digit line 120 (D1*).

During a write operation, a row line 104, which is coupled to transistor 207 and a row line 113 which is coupled to transistor 209 are activated such that if PCRAM memory element 102 is written to a high resistance state, PCRAM element 124 is written to a low resistance state, and vice versa. 30 In this way, PCRAM memory elements 102 and 124 are accessed together and always store complementary resistance digit values. Thus assuming that PCRAM memory element 102 is the primary element which is being written to and read from, a sense amplifier 210 which is coupled to the digit lines 35 118 and 120 will read the value of PCRAM memory element 102 by comparing a discharging precharge voltage on digit line 118 to the discharging precharge voltage on digit line 120 during a memory read operation.

Thus, prior to a memory read, a precharge voltage is 40 applied to complementary digit lines 118 and 120 by a precharge circuit 301. The precharge circuit is activated by a logic circuit on a precharge line which activates transistors 305 to supply a voltage, for example, Vcc/2, to both digit lines 118 and 120.

An equilibrate circuit 303 may also be provided which is activated by an equilibrate signal after the precharge circuit is activated to ensure that the voltages on lines 118 and 120 are the same. The voltages on lines 118 and 120 are held by a parasitic capacitance of the lines. After precharge and equilibrate (if present) circuits are activated, a read operation may be conducted on the complimentary cell pair 300. This read operation is illustrated in greater detail in FIG. 3, which is a simplification of the sense amplifier 210 input path.

Parasitic capacitance for the complementary digit lines 118 and 120 are illustrated as C1 and C1*. The respective access transistors 207 and 209 are illustrated as connected to their respective word lines 105 and 113. The PCRAM memory elements 102 and 124 are also illustrated. As noted, a binary value is stored, for example, in memory PCRAM memory element 102 as a resistance value. It will be either a high resistance value or a low resistance value, and the complementary resistance value will be stored in PCRAM memory element 124.

During a read operation, the precharge voltage applied to 65 the complementary digit lines 118 and 120 is allowed to discharge through the access transistors 207 and 209 and

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through the respective resistance values of the PCRAM memory elements 102 and 124. Because the resistance values will be different, one high and one low, the voltages on the digit lines D1 and D1* (118,120) will begin to diverge during a read operation. Although the voltage initially applied to the complementary digit lines 118 and 120 is a voltage of Vcc/2, during a read operation this voltage actually is slightly higher by approximately 0.3 mV due to the presence of the parasitic capacitance C1 and C1* on the digit lines 118 and 120, as well as gate-drain capacitance inherent within transistors 207 and 209

FIG. 5 illustrates the voltages on the complementary digit lines 118 and 120 during a read operation. The activation of the word lines 105 and 113 is illustrated as a pulse signal, and initially the voltage of Vcc/2+approximately 0.3 mV which exists on both digit lines D1 and D1* begins to decay. Because one PCRAM memory element, e.g. 102, has a higher resistance than the other, the voltage on the digit line associated with the lower resistance value, e.g. 124, will decay faster than the voltage on the digit line coupled to the higher resistance value, e.g. D1. This is illustrated in FIG. 5.

The divergence of the two voltages on the lines D1 and D1* progressively increases. At a predetermined time after the word lines 105 and 113 are activated, the sense amplifier 210 is activated. The sense amplifier can have an architecture typically employed in a DRAM arrangement which is illustrated in FIG. 4. Such a sense amplifier includes an Nsense amplifier latch 302 and a Psense amplifier latch 304. This structure is illustrated in FIG. 4.

Reverting back to FIG. 5, the N sense amplifier is fired first at a time t₁. When the Nsense amplifier fires, the digit line which has the lower voltage, e.g. D1* in the example, is immediately pulled to ground. Thereafter, the Psense amplifier is fired at a time t₂ which drives the higher voltage line, e.g. D1, to Vcc. Accordingly at a time t₂, the sense amplifier 210 outputs a value of Vcc indicating the high resistant state for the PCRAM memory element 102.

Although FIG. 5 illustrates the signal timing which occurs when PCRAM memory element 102 has a higher resistance than memory element 104, obviously the signal levels are reversed if PCRAM memory element 102 has a low resistance state and PCRAM memory element 124 has a high resistance state. That is, the signal diagrams illustrated in the FIG. 5 would have the digit line D1* going towards Vcc and the digit line D1 going towards ground.

FIG. 5 also illustrates another aspect of the invention. As shown, the voltage for row lines 105, 113 increases from near ground level to a positive voltage near Vcc for a read operation. This voltage then returns to near ground level before the sense amplifier is enabled (before t₁). As a result, there is no rewriting of a read PCRAM memory element. If such rewriting of a PCRAM cell is desired, then the voltage on row line 105, 113 having a memory element which is written to a low resistance state, may be at a voltage level near Vcc during operation of the sense amplifier 210, which will automatically rewrite (refresh) the read cell to the low resistance state.

Because programmable contact memory elements are resistive rather than capacitive memory elements, it is possible they will take longer to pull the digit lines up to Vcc and to ground than a typical capacitive memory element found within a DRAM. Supposing that to be true, older DRAM sense amplifier designs that run somewhat slower than the latest generation of DRAM sense amplifiers could also be used with PCRAM memory cells. The advantage of doing so would be that these older DRAM sense amplifiers have already been shown to perform effectively, and their test infrastructure is already confirmed. Consequently, a hybrid

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memory consisting of PCRAM memory elements using DRAM sense amplifiers can be produced having the advantages of PCRAM technology, yet being producible quickly and inexpensively.

Although FIG. 2 shows the complementary programmable 5 contact memory element 102 and 106 and associated access transistors and digit lines D and D* as being provided in the same memory array, the complementary memory elements, access transistors and digit lines may also be provided in respective different memory arrays.

FIG. 6 is a block diagram of a processor-based system 400 utilizing a PCRAM memory device 200 constructed in accordance with one of the embodiments of the present invention. The processor-based system 400 may be a computer system, 15 a process control system or any other system employing a processor and associated memory. The system 400 includes a central processing unit (CPU) 402, e.g., a microprocessor, that communicates with the PCRAM memory device 408 and an I/O device 404 over a bus 420. It must be noted that the bus 420 may be a series of buses and bridges commonly used in a processor-based system, but for convenience purposes only, the bus 420 has been illustrated as a single bus. A second I/O device 406 is illustrated, but is not necessary to practice the 25 invention. The processor-based system 400 also includes read-only memory (ROM) 410 and may include peripheral devices such as a floppy disk drive 412 and a compact disk (CD) ROM drive 414 that also communicates with the CPU 402 over the bus 420 as is well known in the art.

One or more memory devices 200 may be provided on a plug-in memory module 256, e.g. SIMM, DIMM or other plug-in memory module, for easy connection with or disconnection from the bus 420. While the invention has been 35 described and illustrated with reference to specific exemplary embodiments, it should be understood that many modifications and substitutions can be made without departing from the spirit and scope of the invention. Accordingly, the invention is not to be considered as limited by the foregoing description but is only limited by the scope of the appended

What is claimed as new and desired to be protected by Letters Patent of the United States is:

1. A memory device comprising:

first and second digit lines;

first and second programmable resistance memory elements associated with a single memory cell for respectively storing complementary digit values of a data digit 50 as different resistance values and determining the value stored in at least one of the first or second programmable resistance memory elements by discharging respective voltages through the first and second programmable resistance memory elements;

first and second access devices for respectively coupling first and second programmable resistance memory elements to the first and second digit lines; and

- sense circuitry, respectively coupled to the first and second digit lines, for reading the data digit stored as a resis- 60 tance value in one of the memory elements.
- 2. The device of claim 1 further comprising a precharge circuit for precharging the digit lines to a precharge voltage prior to a read operation.
 - 3. The device of claim 1 further comprising: first and second row lines respectively coupled to the first and second access devices; and

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- activation circuitry for substantially simultaneously activating the first and second row lines and the first and second access devices.
- 4. The device of claim 3, wherein when the first and second access devices are activated, the precharge voltage on the digit lines discharges through a respective resistance of the first and second programmable resistance memory elements, and the sense circuitry determines whether one of the first and second programmable memory elements is storing a high or low resistance state and outputs an output digit corresponding to the stored resistance state.
- 5. The device of claim 3, wherein the first and second row lines prevent an automatic refresh of at least one of the first and second programmable resistance memory elements during a read operation.
- 6. The device of claim 2 further comprising an equilibrate circuit for equilibrating the precharge voltage on the digit lines.
- 7. The device of claim 1, wherein the memory device is part of a memory module.
 - 8. A system comprising:
 - a memory cell comprising:
 - a pair of digit lines;
 - a pair of programmable resistance memory elements associated with the memory cell, each of the pair of programmable resistance memory elements storing complementary values of a digit as different resistance values and determining the value stored in the programmable resistance memory element by discharging respective voltages through the programmable resistance memory element;
 - a pair of access devices for respectively coupling the pair of programmable resistance memory elements to the pair of digit lines; and
 - sense circuitry, coupled to the pair of digit lines, for reading the digit stored as a resistance value in one of the pair of programmable resistance memory ele-
- 9. The system of claim 8 further comprising a precharge circuit for precharging the digit lines to a predetermined precharge voltage.
 - 10. The system of claim 8 further comprising:
 - a pair of row lines respectively coupled to the pair of access devices; and
 - activation circuitry for activating the pair of row lines and the pair of access devices.
 - 11. The system of claim 10, wherein when the pair of access devices are activated, the precharge voltage on the pair of digit lines discharges through a respective resistance of the pair of memory elements, the sense circuitry determines whether the one of the pair of memory elements is storing a high or low resistance state and outputs a value corresponding to the stored resistance state.
- 12. The system of claim 9, wherein the pair of digit lines have an associated parasitic capacitance which stores the precharge voltage.
- 13. The system of claim 12, wherein the parasitic capacitance stores a voltage value which is larger than the precharge voltage.
- 14. The system of claim 8, wherein the pair of memory elements are in a common memory array.
- 15. The system of claim 8, wherein the pair of memory elements are in different memory arrays.
- 16. The system of claim 9 further comprising an equilibrate circuit for equilibrating the precharge voltage on the pair of digit lines.

- 17. A memory device comprising:
- a circuit for storing a value as respective different higher and lower resistance states in a pair of programmable resistance memory elements, determining the value stored in one of the memory elements by discharging respective voltages through the memory elements and comparing the discharging voltages, and for rewriting the value stored only in one of the memory elements which is storing a lower resistance state.
- 18. The device of claim 17, wherein the circuit precharges 10 a pair of digit lines, which are respectively switchably coupled to the memory elements, to a common voltage value, and respectively discharges the voltage on each of the digit lines through each of the memory elements.

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- 19. The device of claim 18, wherein the common voltage value on the digit lines is discharged through the memory elements by enabling access devices associated with each of the memory elements.
- 20. The device of claim 19, wherein the circuit determines whether the discharging voltage associated with one of the memory elements is the higher or lower of the two discharging voltages and outputs a first value if the discharging voltage associated with the first of the memory elements is the higher voltage and outputs a second value if the discharging voltage associated with the first of the memory elements is the lower voltage.

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